

REC'D PTO

28 NOV 2005

10/537,511 GAU: 28/3

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ALL REFERENCES CONSIDERED EXCEPT WHERE LINED THROUGH. //sjs// PATENT
ATTORNEY DOCKET NO. 046124-5389

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re Application of: Fumitsugu FUKUYO et al.)	Confirmation No.: 4722
)	
U.S. Application No.: 10/537,511)	Group Art Unit: Unassigned
)	
Filed: June 3, 2005)	Examiner: Unassigned
)	
For: LASER PROCESSING APPARATUS)	

Commissioner of Patents
MAIL STOP PCT

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Sir:

INFORMATION DISCLOSURE STATEMENT UNDER 37 C.F.R. § 1.97(b)

Pursuant to 37 C.F.R. §§ 1.56 and 1.97(b), Applicant brings to the attention of the Examiner the documents listed on the attached PTO-1449. This Information Disclosure Statement is being filed before the mailing date of a first Office Action on the merits for the above-referenced application.

International Search Report dated March 23, 2004 is attached together with a copy of each document listed on the PTO Form 1449 that is not a U.S. patent or U.S. patent publication.

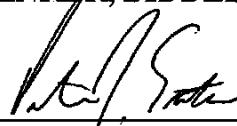
Applicants respectfully request that the Examiner consider the listed documents and evidence that consideration by making appropriate notations on the attached form. As for any document listed on the accompanying PTO-1449 that is in a language other than English, relevance can be understood from an enclosed English abstract or at least partial translation or from mention in the specification or search report for a corresponding application.

This submission does not represent that a search has been made or that no better art exists and does not constitute an admission that the listed document is material or constitutes "prior art." If it should be determined that the listed document does not constitute "prior art" under United States law, Applicants reserve the right to present to the Office the relevant facts and law regarding the appropriate status of such document. Applicants further reserve the right to take appropriate action to establish the patentability of the disclosed invention over the listed document, should the document be applied against the claims of the present application.

If there is any fee due in connection with the filing of this Statement, please charge the fee to our Deposit Account No. 50-0573.

Respectfully submitted,

DRINKER, BIDDLE & REATH LLP



Peter J. Sistare

Registration No. 48,183

Dated: November 28, 2005

CUSTOMER NO. 55694

DRINKER, BIDDLE & REATH LLP

1500 K Street, N.W., Suite 1100

Washington, D.C. 20005-1209

Tel: (202) 842-8800

Fax: (202)-204-0289

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INFORMATION DISCLOSURE CITATION (Use several sheets if necessary) PTO Form 1449	Attorney Docket No. 046124-5389	Serial No. 10/537,511
	Applicants Fumitsugu FUKUYO et al.	
	Filing Date June 3, 2005	Group 2873 Unassigned

U.S. PATENT DOCUMENTS

*Examiner Initial	Document Number	Date	Name	Class	Sub Class	Filing Date
//sjs//	2004/0002199	Jan. 1, 2004	Fukuyo et al.	438	460	Mar. 12, 2003
//sjs//	6,392,683	May 21, 2002	Hayashi	347	241	Sept. 23, 1998

FOREIGN PATENT DOCUMENTS

	Document Number	Date	Country	Class	Sub Class	Translation YES NO	
//sjs//	05-212571	Aug. 24, 1993	JP	—	—	Abstract	
//sjs//	03-018979	Jan. 28, 1991	JP	—	—	Abstract	
//sjs//	1 338 371	Aug. 27, 2003	EP	—	—		

OTHER DOCUMENTS (Including Author, Title, Date, Pertinent Pages, Etc.)

//sjs//	Kiyotaka MIURA et al., "Formation of Photo-induced Structures in Glasses with Femtosecond Laser", Dai 42 Kai Proceedings of Laser Materials Processing Conference, November 1997, pp. 105 – 111 (Including English-language abstract)
//sjs//	Ken-ichi HAYASHI, "Inner Glass Marking by Harmonics of Solid State Laser", Dai 45 Kai Proceedings of Laser Materials Processing Conference, December 1998; pp. 23 – 28 (Including English-language abstract)
//sjs//	Tomokasu SANO et al., "Evolution of Processing Characteristics of Silicon With Picosecond Pulser Laser", Osaka University, Graduate School, Department of Technological Research, April 2000, pp. 72-73 (Including English-language translation)
//sjs//	Shuji TAKAOKA, "Stealth Dicing, Its Principles and Features: A Technology Most Suitable for Dicing Very Thin Semiconductor Wafers", September 2002, pp. 17-21 (Including English-language translation)

Examiner /Scott J. Sugarman/	Date Considered 03/06/2008
Examiner: Initial if reference considered, whether or not citation is in conformance with MPEP 609; draw line through citation if not in conformance and not considered. Include copy of this form with next communication to applicant.	